



to produce consistent high-quality cavities which can live dn

niobium cavities. Such a project demands



University

## esearch Optical Inspection for **Of** Z 0 て bium SRF Cavities Students

# Introduction

Niobium SRF cavities have very important applications, particularly in particle accelerator machines, due to their high Q-factors and niobium cavities. Such a project demands the ability to consistently produce high quality cavities which meet project specifications. are limited by quenches. Much research is being done to understand the causes of these phenomena and develop methods of elim to their theoretical potential in the near future. and the good mechanical properties of niobium. ons. Currently this ability does not exist. Cavities eliminating them. ability does not exist. Groups like CLASSE at Cornell University are often fall short The International Linear Collider will require some 18,000 nine cell developing fabrication techniques and procedures 0f their theoretical field limits due to Q-slopes and

region

quench region

No defects were

-No system to measure where you are in a defects Light source is point-like which produces glare and uneven lighting Must re-align microscope with mirror Tube is unsupported and must rest inside the cavity for every new cavity and record locations cavity which is time of

consuming

The New sys

Ν 

part of

ongoing research.

Methods of injecting the epoxy and removing it successfully once cured are

-Tube is supported and mounted to rails and does not touch cavity -Z, θ coordinate system to measure the loc -System is always aligned and set-up time is Electroluminescent panels provide uniform lighting ation of defects minimal accurately

θ

shell PVC heat shrink

better images and tell you exactly where The new system will provide a faster way of inspecting cavities, produce useful for computer simulations or other



NANY PERSO

# **New Inspection System**

had several limitations and a new system for inspection has been to inspect the inner surfaces of cavities a special system is a source of light. The previous system required

to peer into the cavity and provide

developed.

In order

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The old Syst



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Ħ ש neans defect is located which can be of analysis.

performed and a digital map of the defect can be made.

in cast is taken of the mold so profilometry can be

Once removed, a hard res

# poxy Molds of defects

convey depth very accurately. about surface defects is to take a mold of the region where the defect is Inspection photographs  $\cap$ an provide a lot of information but they do not One approach to obtaining more information

located in order to perform profilometry measurements.



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silicon mold.

removed any defects A silicone epoxy is poured







## 2010



visible,

to remove

gas the

cavity. Many bubbles are

A test pour in a cut-open

under vacuum.

epoxy is out-gassed

